

**Title of Invention: SUBSTRATE PROCESSING APPARATUS, SUBSTRATE
PROCESSING SYSTEM, ELECTRICAL POWER SUPPLY SYSTEM, AND
ELECTRICAL POWER SUPPLY METHOD**

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Abstract

The present invention is a substrate processing device which processes
substrates, said device comprising a power receiving unit which includes a power
receiving coil along which electrical power is transmitted in a non-contact manner
10 from a power transmission coil located outside the substrate processing device,
wherein electrical power is supplied to at least one unit or member that uses
electrical power from the power receiving unit.

Fig. 5

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